



Application No. (if known): 10/812,747

Attorney Docket No.: 20110/0200839-US0

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Response to Restriction Requirement (with Traverse) (2 pages) Return Receipt Postcard



Docket No.: 20110/0200839-US0

(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Kazuo Kasai et al.

Application No.: 10/812,747

Confirmation No.: 5489

Filed: March 29, 2004

Art Unit: 1765

For: SILICON SUBSTRATE ETCHING METHOD

Examiner: L. Vinh

AND ETCHING APPARATUS

RESPONSE TO RESTRICTION REQUIREMENT

MS Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

In response to the restriction requirement set forth in the Office Action mailed February 27, 2006 (Paper No. 022206), Applicants hereby provisionally elects Group II: Claims 15-24 for continued examination, with traverse.